

DYNAMIC OVERDRIVE COMPENSATION TEST SYSTEM AND METHOD

ABSTRACT

The invention(s) relates to a wafer test system including means capable of
5 communicating an overdrive to a chuck, the chuck moving a wafer towards a probe head
responsive to the overdrive, measuring a contact resistance of at least one channel in each of a
plurality of dies associated with the wafer using the probe head, computing a per channel
standard deviation responsive to measuring the contact resistance, comparing the standard
deviation on the at least one channel to a threshold, and increasing the overdrive responsive
10 to the comparison.